

FORM PTO-1449
(REV. 7-80)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.
97-P-149D1
(850063.518D1)

EXPRESS MAIL NO.
EL897859635US


INFORMATION DISCLOSURE STATEMENT
(Use several sheets if necessary)

APPLICANT
Ming Michael Li

FILING DATE
February 6, 2002

GROUP ART UNIT
2825

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
PAR IA	AA	5,182,232	01/26/93	Chhabra et al.	437	200	
PAR	AB	5,394,012	02/28/95	Kimura	257	739	
PAR	AC	5,418,188	05/23/95	Harper et al.	437	200	
PAR	AD	5,585,295	12/17/96	Wu	437	44	
PAR	AE	5,599,746	02/04/97	Lur et al.	437	200	
PAR	AF	5,767,013	06/16/98	Park et al.	438	622	
PAR	AG	5,877,063	03/02/99	Gilchrist	438	398	
PAR	AH	5,993,685	11/30/99	Currie et al.	252	79.1	
PAR IA	AI	6,074,926	06/13/00	Cathey et al.	438	398	
	AJ						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AK					
	AL					
	AM					
	AN					
	AO					

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

PAR IA	AP	Chang, C.Y. and Sze, S.M., "ULSI Technology," 1996, The McGraw-Hill Companies, Inc., pp. 229, 395-397
PAR IA	AQ	Wolf, S., "Silicon Processing for the VLSI Era," Vol. 2 - Process Integration, 1990, Lattice Press, pp. 45, 354-357.
	AR	

EXAMINER Reuto N. Rock DATE CONSIDERED 9/29/2004 3/30/05

* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).